

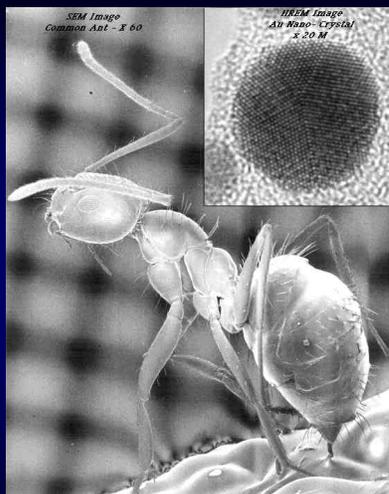
Microscopy: From Ants to Atoms

Nestor J. Zaluzec
Argonne National Laboratory
Materials Science Division

Microscopy is one of the few methodologies applied to nearly every field of science and technology in use today.

A microscope can be as simple as a hand held optical device or as complex as a multi-million dollar research tool.

Using these instruments, both scientists and students can explore the synergistic relationships of structure and properties of a wide variety materials in both the Physical and the Life Sciences.



Why Microscopy ?

- Resolution of the Human Eye ~ 0.1 mm
- Apparent resolution of the Eye for a Magnified Object is:

• $R \sim \frac{0.1 \text{ mm}}{\text{Magnification}}$

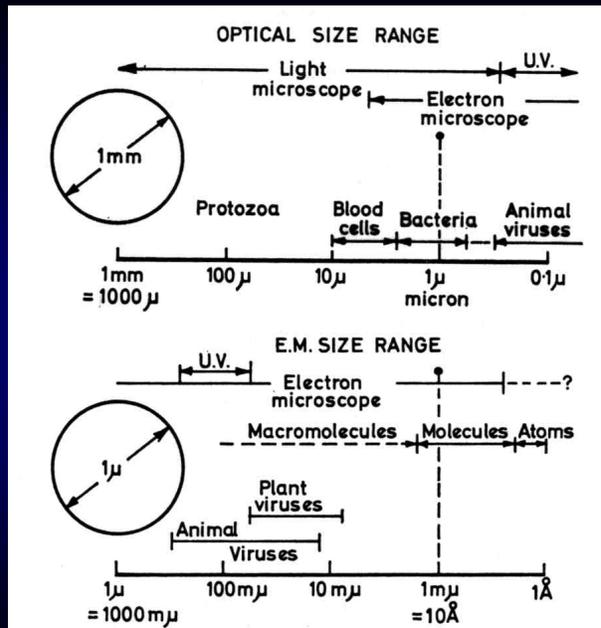
Magnification	Resolvable Distance
100	1 μm - (10,000 Å)
1,000	0.1 μm - (1,000 Å)
10,000	0.01 μm - (100 Å)
1,000,000	0.0001 μm - (1 Å)

- What is the difference between Magnification and Resolution?

Magnification: Apparent enlargement of an object

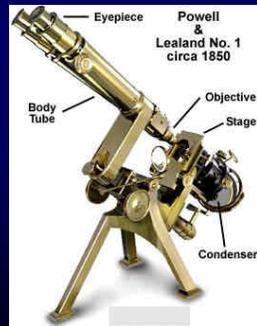
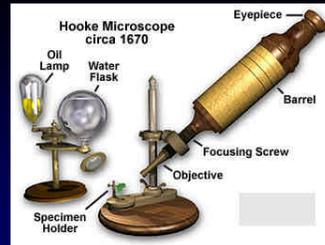
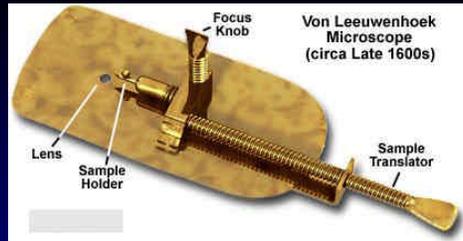
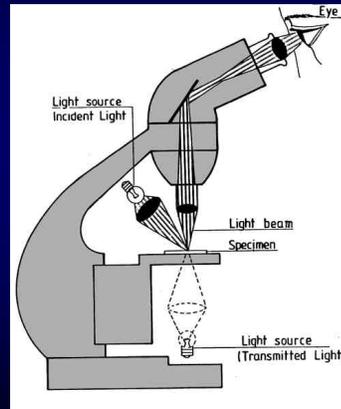
Resolution: Capability of making distinguishable the individual parts of an objects

How Small is Small?

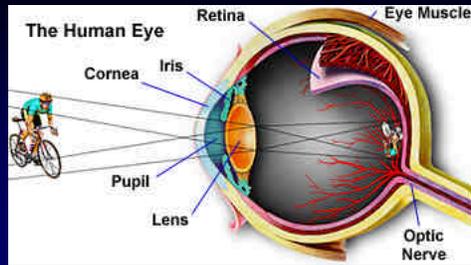


Basic Components of an Optical Microscope

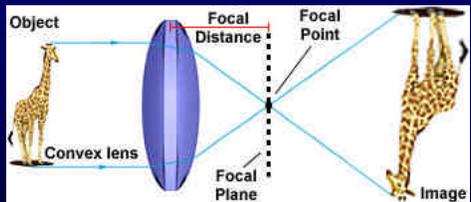
- Illumination Source
- Illumination Lens
- Specimen
- Magnifying Lens
- Viewer



Lenses are Simple

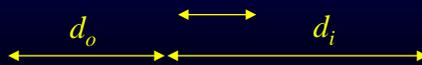


Thin Lens Formulae



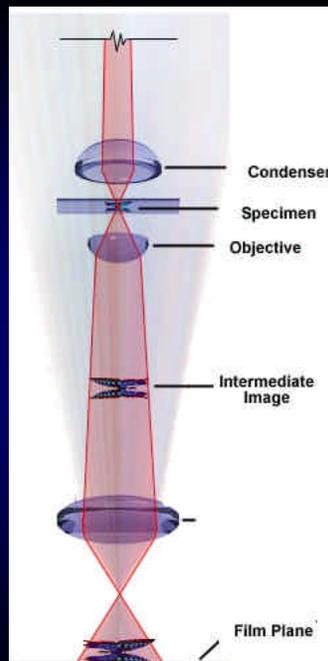
$$\frac{1}{f} = \frac{1}{d_o} + \frac{1}{d_i}$$

$$M = -\frac{d_i}{d_o}$$



Compound Microscope

Higher Magnification is achieved by
Stacking Lenses
 $M = M_1 * M_2 * M_3$



What are the limits of Resolution?

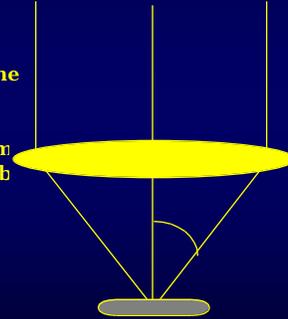
Abbe (Diffraction) Limit:

Defines the minimum resolvable distance between the image of two point objects using a perfect lens.

In any magnifying system a point object (i.e. zero dim) cannot be imaged as a point but is imaged as a distrib intensity having a finite width.

$$\text{Resolution of an imaging system} = \frac{0.61 \lambda}{\text{sin } (\alpha)}$$

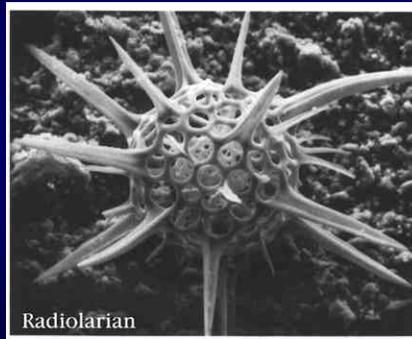
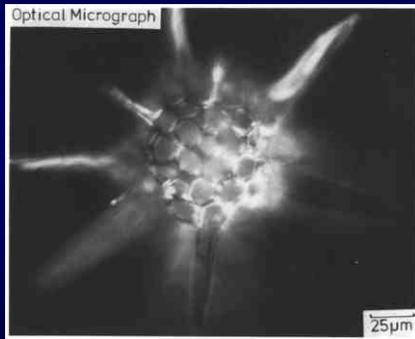
- = wavelength of the imaging radiation
- = index of refraction of the lens
- = illumination semi-angle



Light vs Electrons

Light Microscope	Electron Microscope
= 0.5 μm	$\sim \sqrt{\frac{150}{V_0}} = 0.055 \text{ \AA} \text{ (@50 kV)}$
= 1.5 (glass)	= 1.0 (Vacuum)
= 70°	= 1°
= 0.2 $\mu\text{m} = 2000 \text{ \AA}$	= 0.00016 $\mu\text{m} = 1.6 \text{ \AA}$

Depth of Field



Depth of Field

The distance parallel to the optical axis of the microscope that a feature on the specimen can be displaced without loss of resolution

Optical Microscope

$$d = \frac{\sqrt{\lambda^2 - (NA)^2}}{(NA)^2} + \frac{250}{M^2}$$

Electron Microscope

$$d = \frac{0.1 \text{ mm}}{M}$$

= wavelength
= refractive index
= semi angle

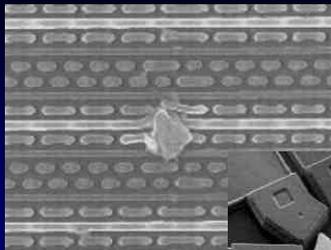
M = total magnification

NA= Numerical Aperture of lens

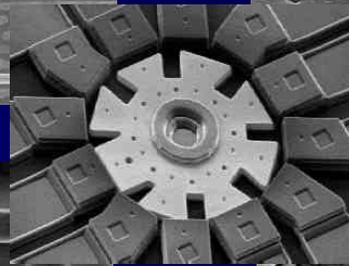
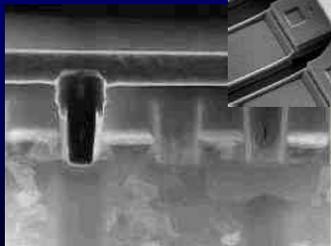
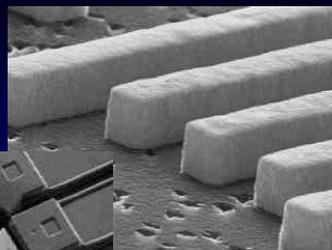
Depth of Field

Magnification	Depth of Focus	
	Optical	SEM
10	60 μm	1000 μm
100	8 μm	100 μm
1,000	0.2 μm	10 μm
10,000	-	1 μm

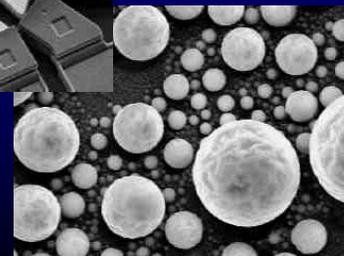
Periodic Arrays



Critical Dimension Measurements

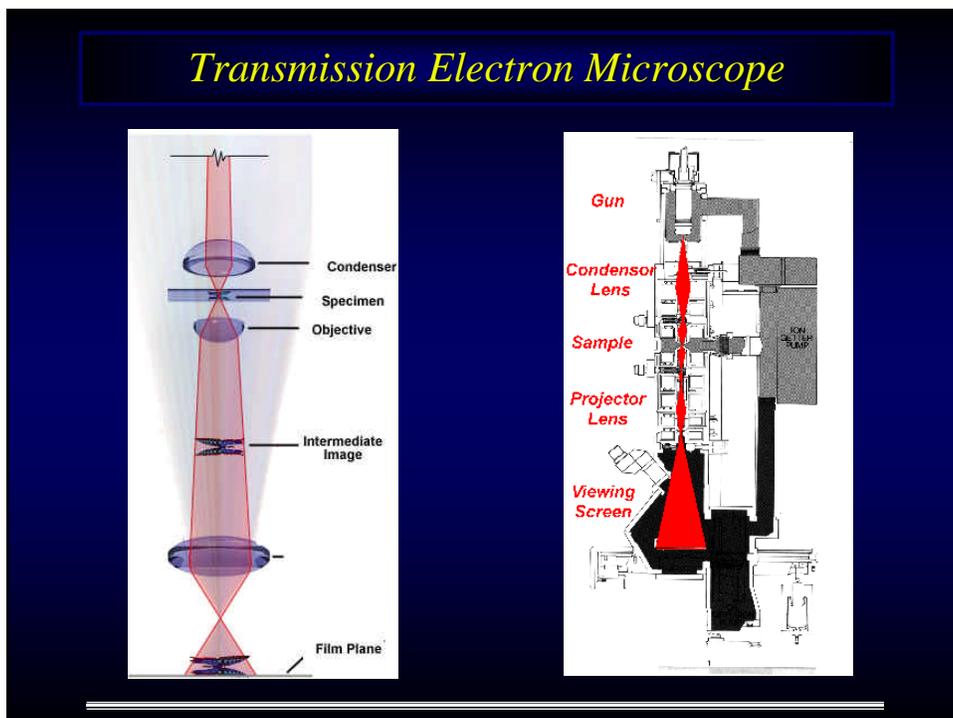
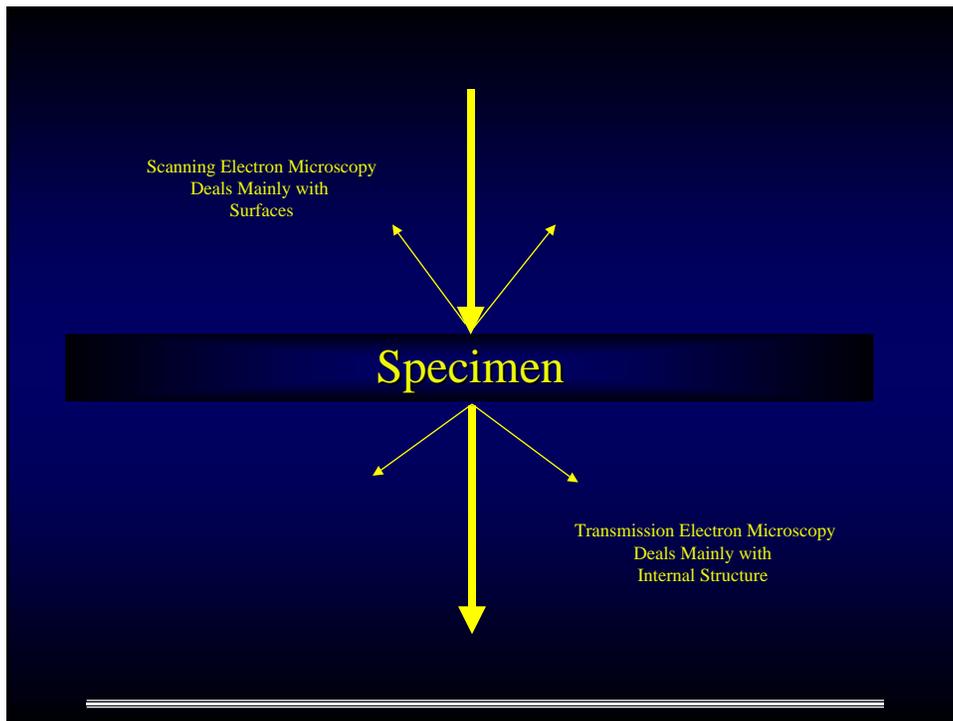


MEMS



NanoScale Electronic/Magnetic Devices

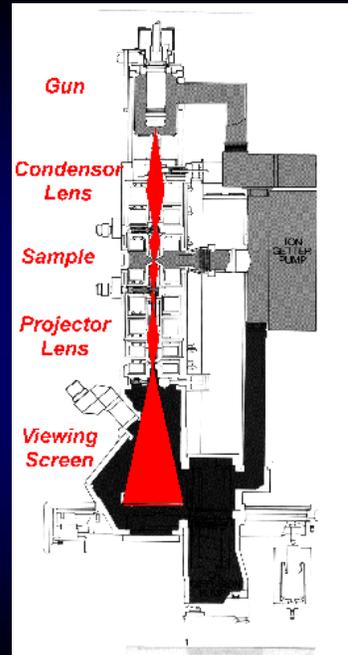
Non-Equilibrium Materials



Basic Components of an Electron Microscope

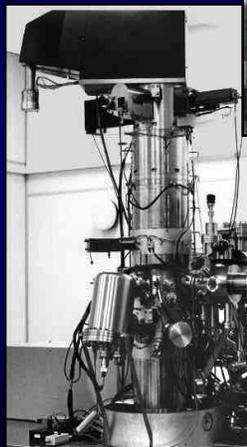


Transmission Electron Microscope



ANL - Advanced Analytical Electron Microscope

- **Cold Field Emission Electron Source**
 - V_0 : 50 - 300 kV
- **Ultrahigh vacuum (UHV) environment**
 - $\sim 1 \times 10^{-11}$ torr - Gun, $< 2 \times 10^{-10}$ torr - Column
 - $< 5 \times 10^{-10}$ torr - Specimen Preparation Chamber
- **Electron Optics capable of :**
 - STEM / SEM:
 - TEM:
 - CBED/SAED:
 - Other Modes: TSEM, TSED, RHEED
- **Side Entry Goniometer Stages**
 - RT Double Tilt Beryllium:
 - LN₂ Cooled Double Tilt Be Stage:
 - Single Tilt Heating Stage:
- **Analytical SubSystems on the E/O Column**
 - XEDS, EELS, AES
- **Specimen Preparation Chamber**
 - High Pressure/Temperature Gas Reaction Cell
 - Thin Film Evaporation Chamber
 - Mini-SIMS system - Gallium LMIS, Quad Mass Analyzer
 - RV LEED & Vacuum Transfer Vessel
 - ANL MultiPort Station for development work.
- **Computer Control**
- **Special Objective Lens Port Configuration**
 - 7 Experimental Ports on Objective Lens for Analytical Equipment
 - 3 Additional Ports for Electrical Feedthrus etc...



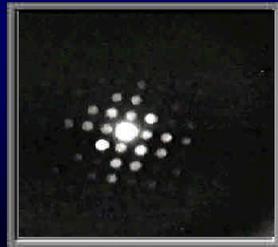
Transmission Electron Microscopy



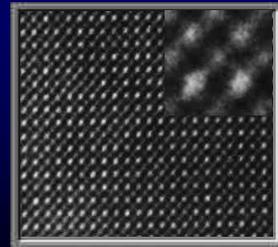
Conventional Imaging



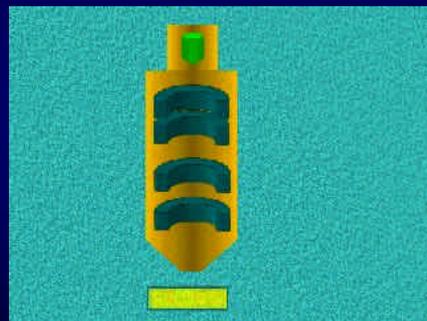
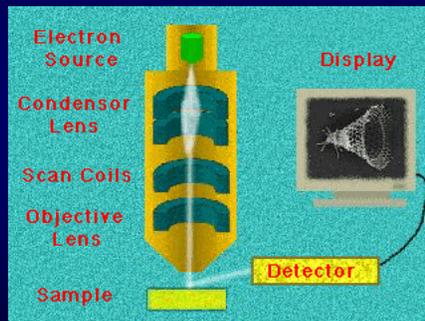
High Resolution Imaging



Diffraction

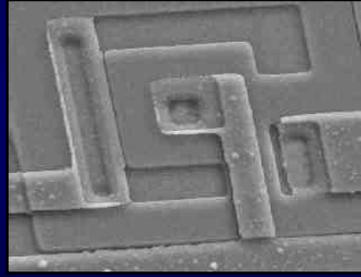


Basic Components of a Scanning Electron Microscope

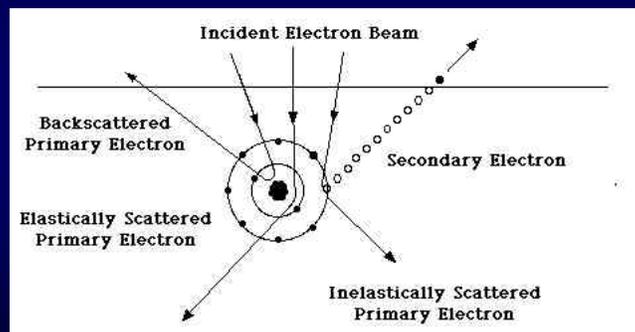


Scanning Electron Microscope

Scanning Electron Microscope



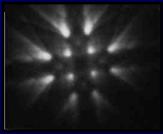
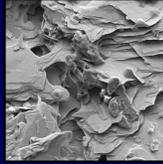
Sources of Electron Emission from the Sample



MicroCharacterization via Electron Microscopy

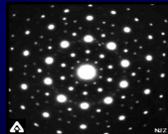
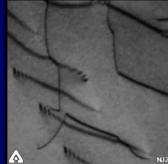
SEM

Scanning Electron Microscopy



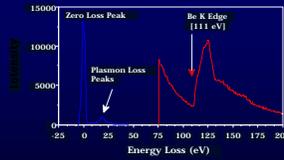
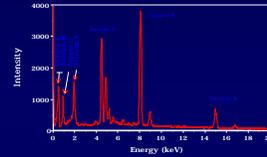
TEM - STEM - HREM

Transmission - Scanning Transmission - High Resolution Electron Microscopy



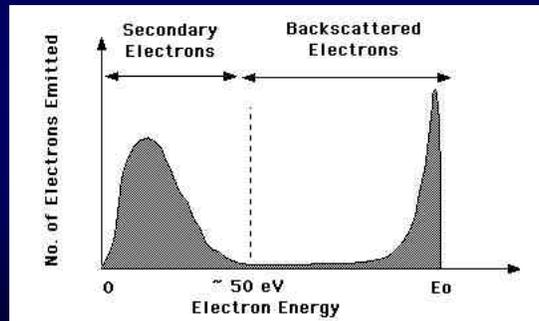
AEM

Analytical Electron Microscopy

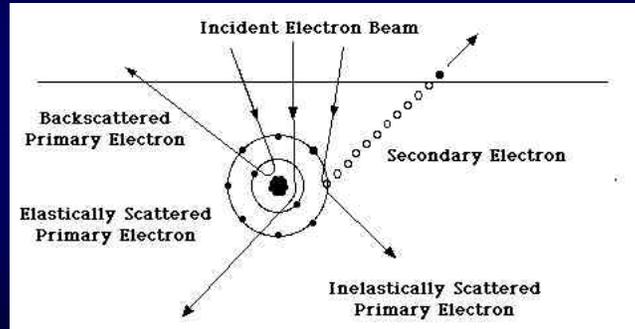


Morphology, Crystallography, Elemental, Chemical, Electronic Structure

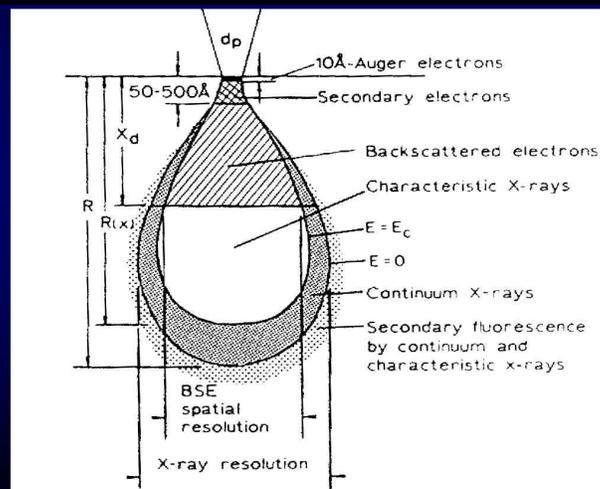
Electron Energy Distributions



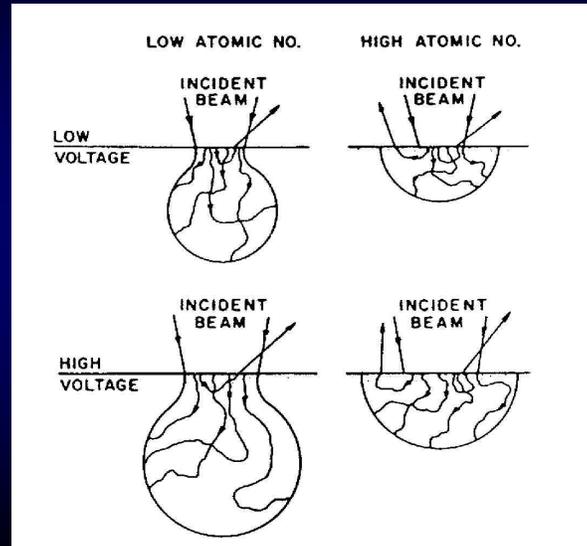
Sources of Electron Emission from the Sample



How deep does the signal come from?



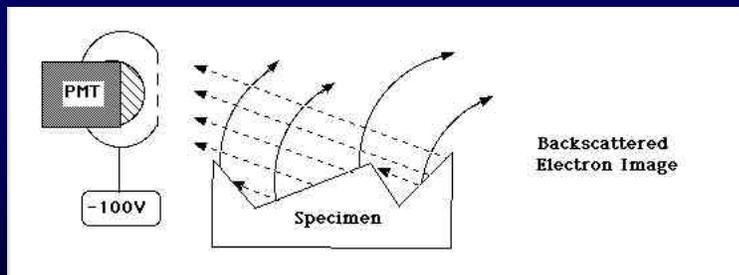
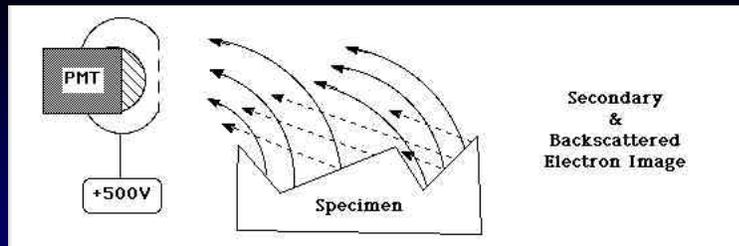
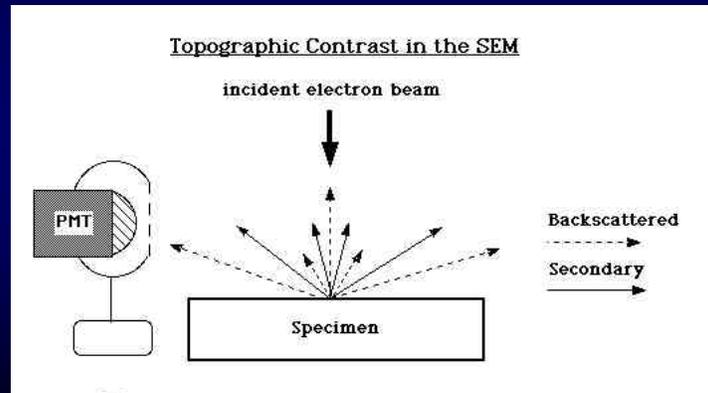
*Electron - Solid Interactions Determine
the “Depth” of Information*



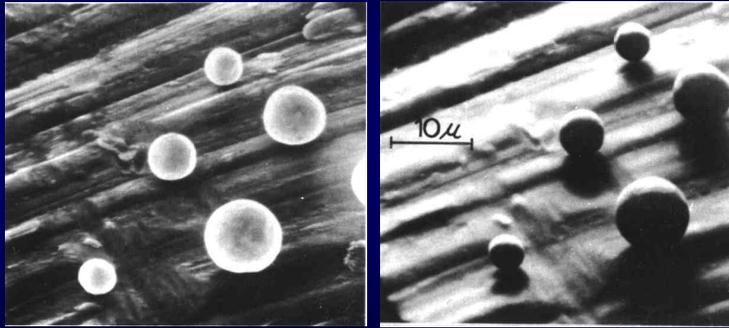
Contrast in an SEM Image

- **Topographic Contrast**
- **Atomic Number Contrast**
- **Voltage Contrast**
- **Magnetic Contrast**
- **Electron Beam Induced Current**
- **Cathodoluminescence**
- **Electron Channeling Contrast**
- **Electronic/Digital Signal Processing**
- **Characteristic X-ray Emission**

Contrast in an SEM Image

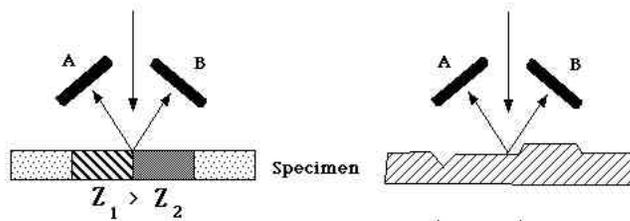


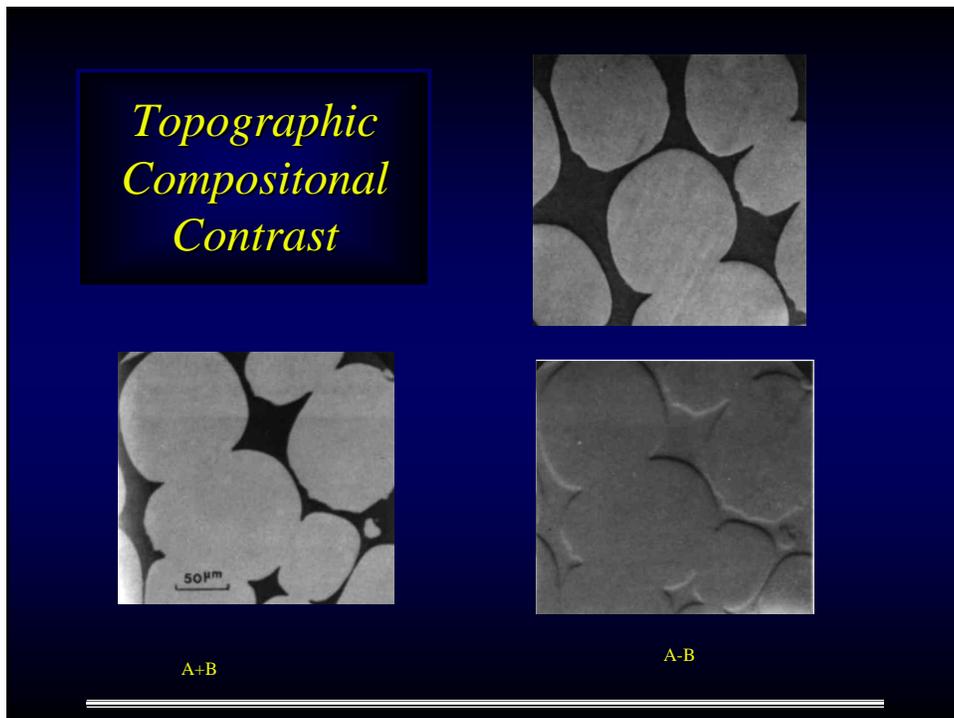
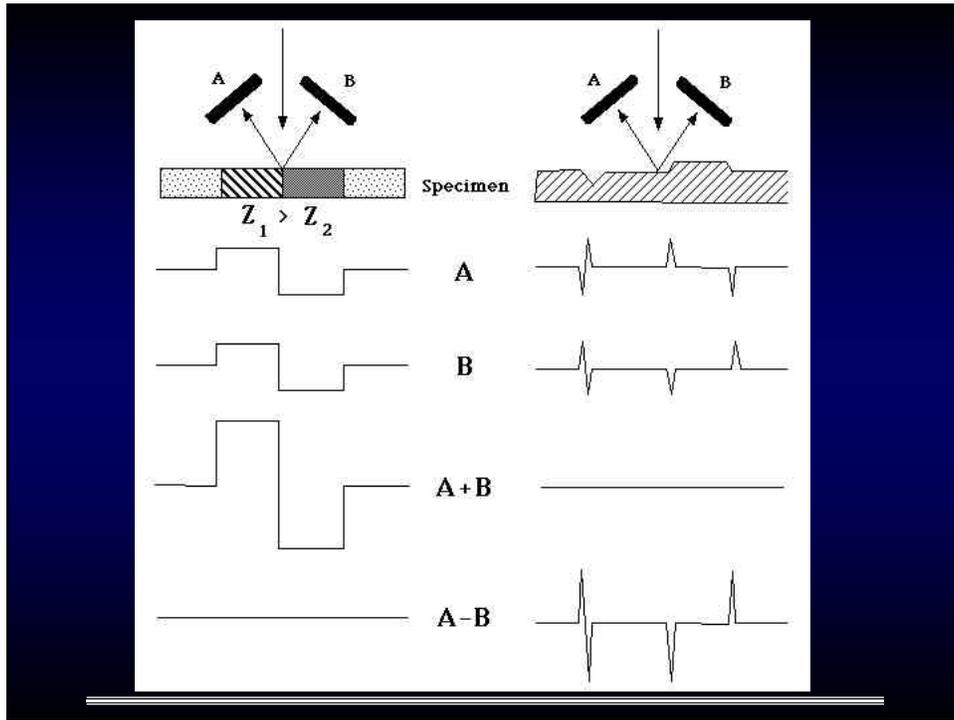
SEI vs BSI



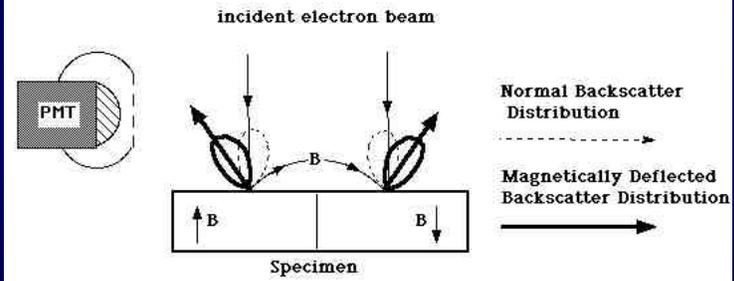
Topo/Compo Contrast Using Multiple Detectors

Contrast Enhancement/Suppression using Signal Mixing

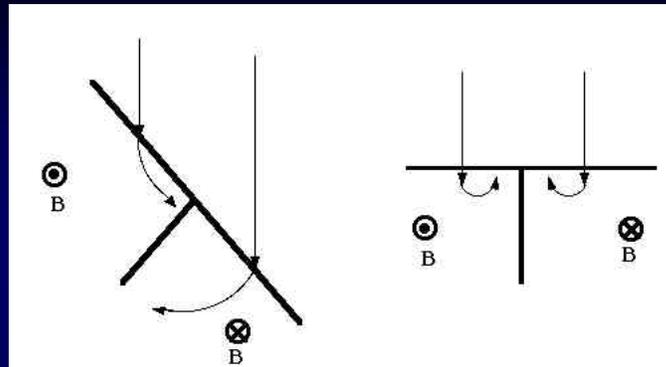




Magnetic Contrast

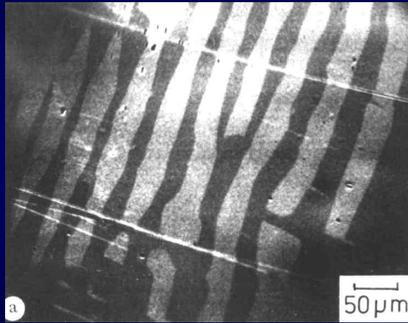


Type I Magnetic Contrast / External B Field

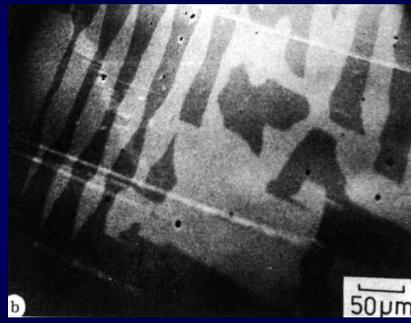


Type II Magnetic Contrast / Internal Fields

Magnetic Contrast

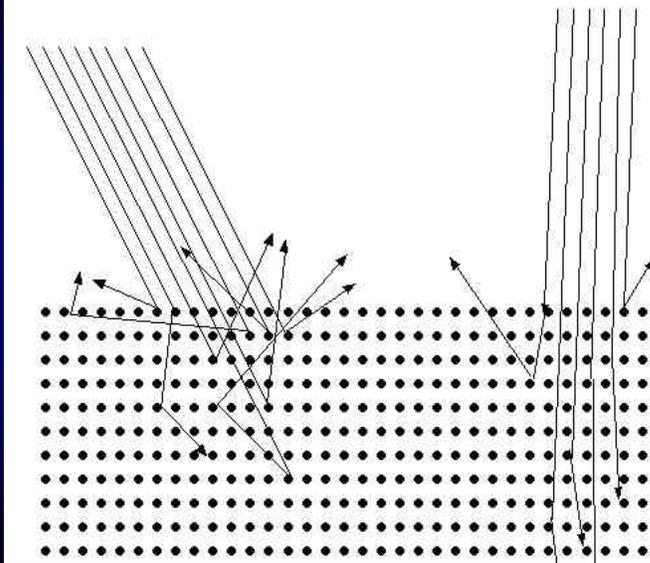


No Field

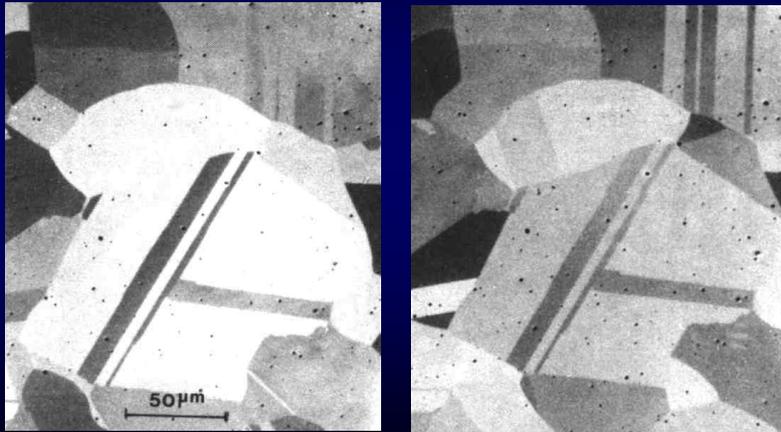


Field On

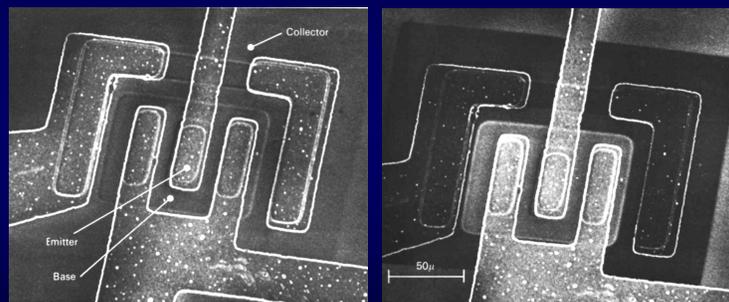
Electron Channeling Contrast



Channeling Contrast



Voltage / Current Contrast



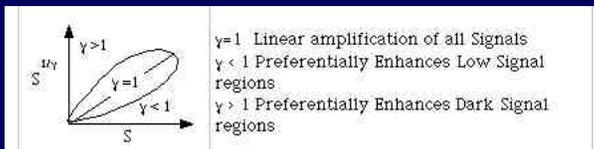
Electronic/Digital Signal Processing

This contrast methodology is independent of the actual contrast mechanism operating in the solid, however, it is sometimes critical in determining the visibility of a signal generated by the electron-solid interaction. Today this may be done either on-line by analog processing or off-line using digital signal processing methods and dedicated image processing systems

- Black Level Suppression
- Non-Linear Amplification
- Differentiation
- Signal Mixing
- Digital Processing



Black Level Suppression

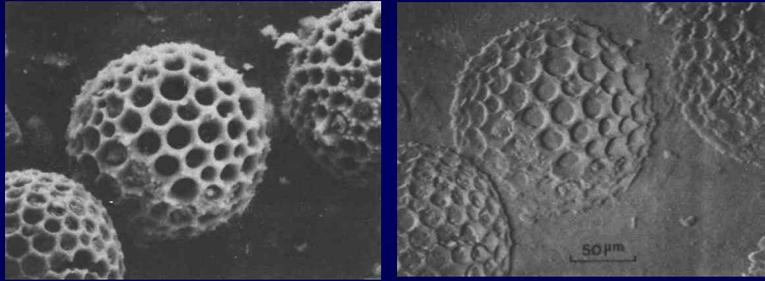


Non-Linear Amplification



Differentiation

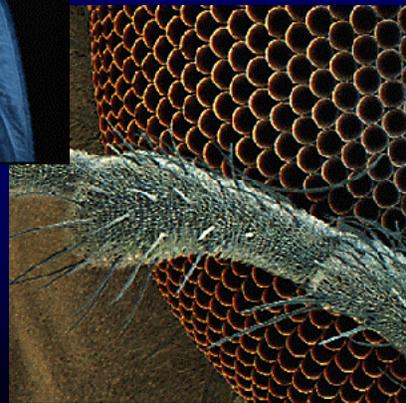
Digital / Electronic Processing



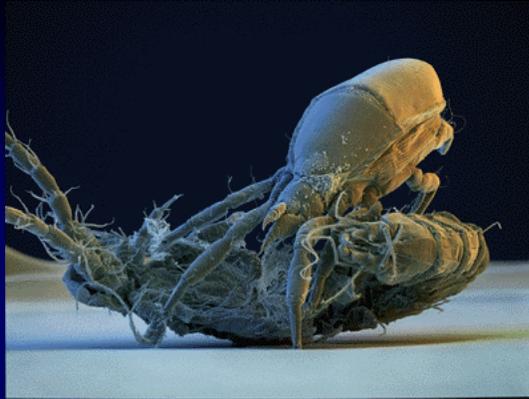
Images of the World Around Us



Colorized SEM Micrographs
Courtesy of David Scharf



Black Fly



Mite Feeding on Mistococrad

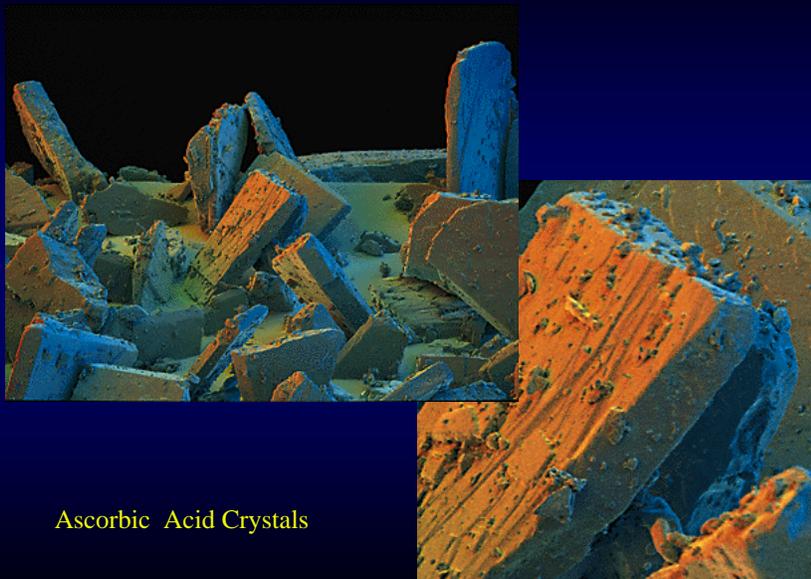


Deer Tick

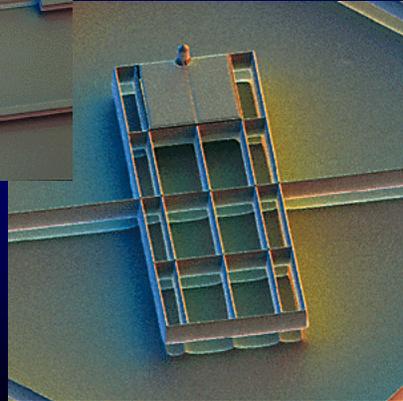
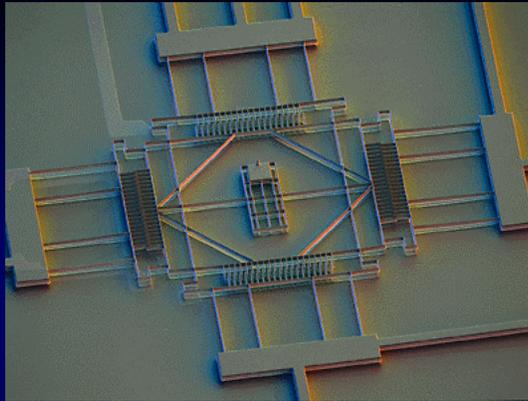




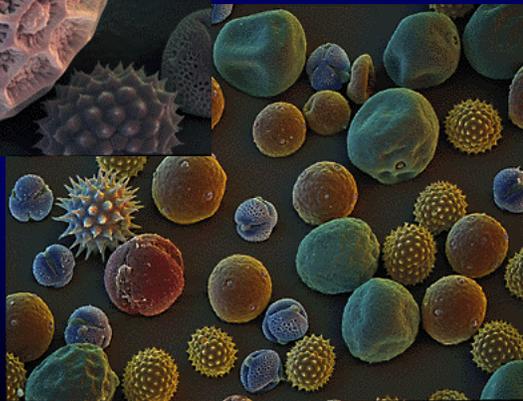
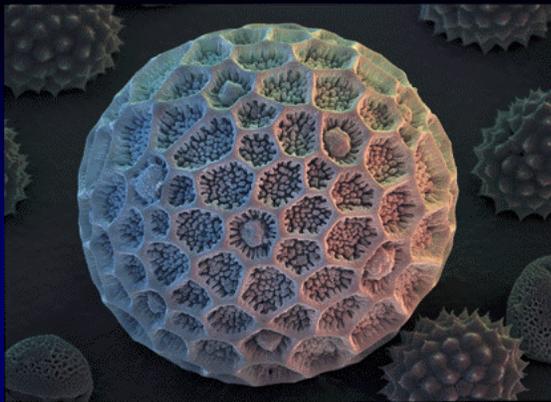
Female Mosquito



Ascorbic Acid Crystals



NanoFabrication Microelectronics



Pollen Grains

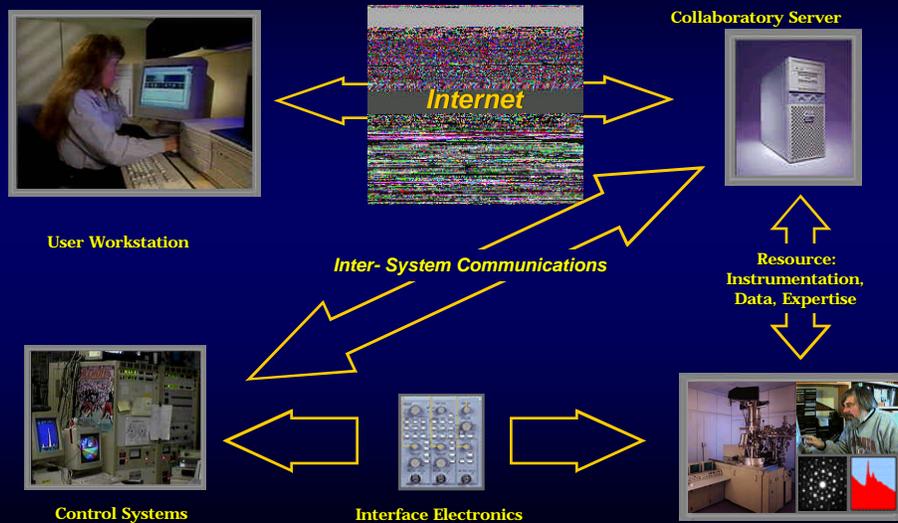
Microscopy Resources

<http://tpm.amc.anl.gov> - TelePresence Microscopy Site

<http://www.amc.anl.gov> - M&M WWW Site

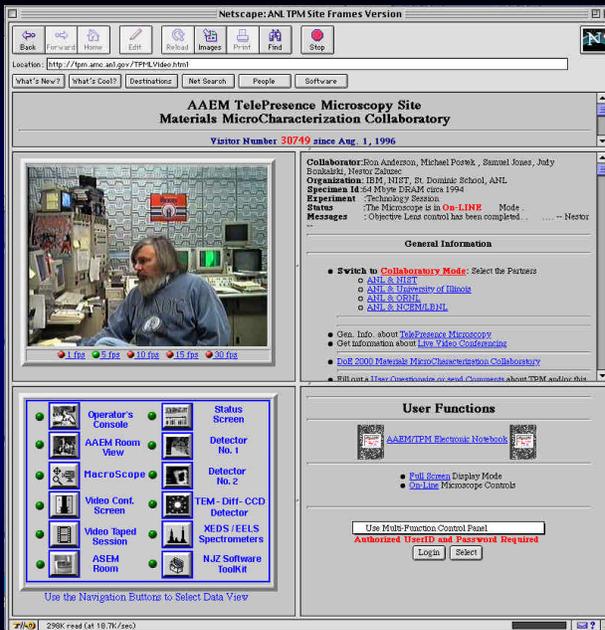
<http://www.msa.microscopy.com/MicroScape/MicroScape.html>
<http://www.msa.microscopy.com/ProjectMicro/PMHomePage.html>
<http://www.msa.microscopy.com>

TelePresence Microscopy Collaboratory Architecture



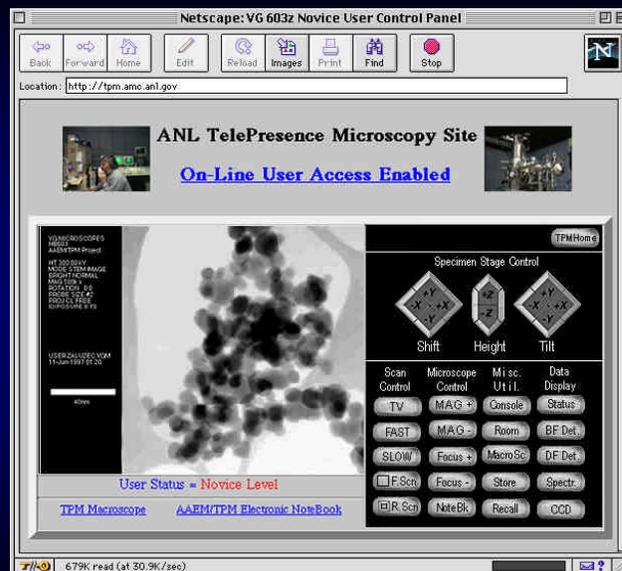
**ANL -
WWW
TPM Server**

*Provides
Platform
Independent
Access*



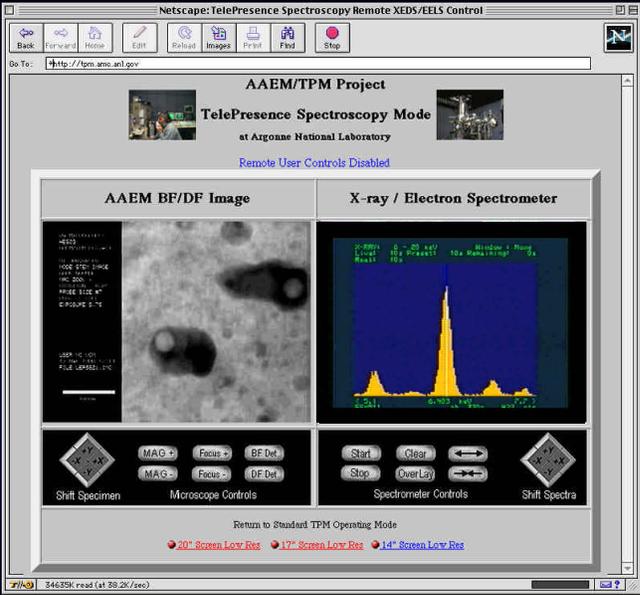
**On-Line
Instrument
Control**

**Platform
Independent
WWW
Interface**



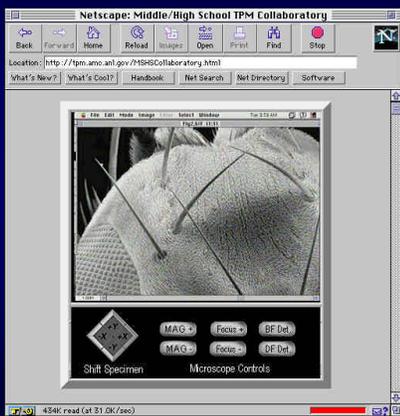
On-Line Instrument Control

Platform Independent WWW Interface



TelePresence Microscopy

Middle/High School Collaboratories



Netscape Client on Mac's & PC's in Classroom provides simple and inexpensive interface where students and remote instructors can interact with Microscopes.



Live Video Conferencing using "CuSeeMe" provides low cost interactions between Instructor and Students

Middle/High School Collaboratories



Materials MicroCharacterization Collaboratory

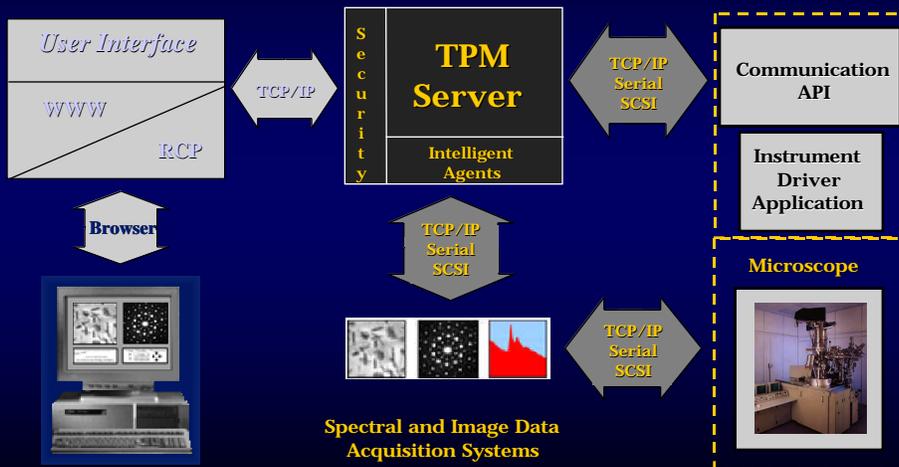
Materials MicroCharacterization Collaboratory
TelePresence Microscopy Facilities

ARGONNE NATIONAL LABORATORY NIST ORNL Univ. of Illinois
Urbana-Champaign

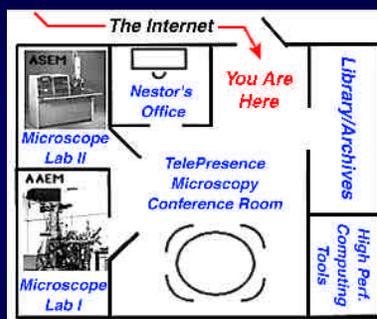
<u>ANL</u> 	<u>NIST</u> 	<u>Univ. of Illinois</u>
<u>ORNL</u> 	<u>NCEM/LBNL</u> 	Non WWW-Solutions Other Methods of TelePresence Operation <u>LBNL - ITG</u> <u>ORNL - MAUC</u>

<http://tpm.amc.anl.gov/mmc>

Current Architecture Instrument Access/Control



TelePresence Microscopy Collaboratory



<http://tpm.amc.anl.gov>

Network Based Video Conferencing is Possible, but Immature



TelePresence Microscopy

Provides Access to:

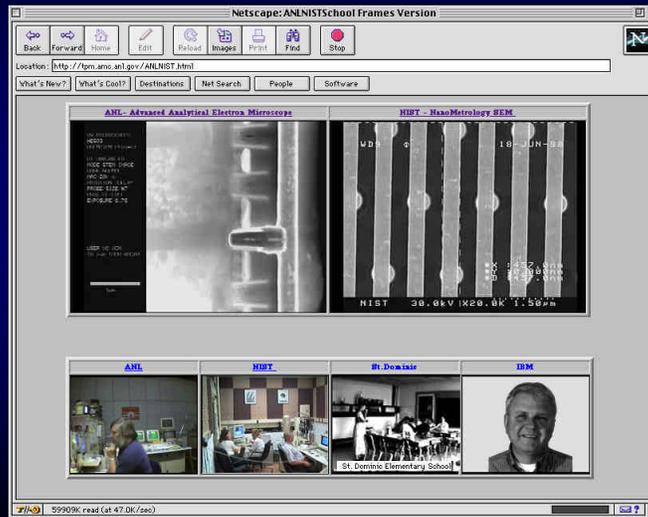
- Instrument Room
- Instrument Status
- Experimental Data
- On-Line Control
- Video Conferencing

August 4, 1995
12:48:46 PM

Step	Time	Temp	Pressure	Flow	Flow	Flow	Flow	Flow	Flow
1	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
2	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
3	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
4	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
5	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
6	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
7	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
8	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
9	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
10	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
11	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
12	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
13	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
14	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
15	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
16	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
17	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
18	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
19	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
20	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
21	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
22	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
23	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
24	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
25	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
26	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
27	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
28	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
29	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
30	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
31	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
32	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
33	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
34	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
35	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
36	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
37	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
38	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
39	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
40	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
41	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
42	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
43	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
44	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
45	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
46	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
47	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
48	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
49	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000
50	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000	0.000

• Electronic

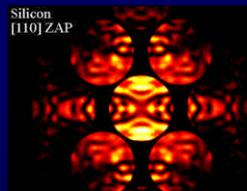
Middle/High School Collaboratories



TelePresence Collaboration Key to All Scientific Experiments is the Interaction of Investigators with:



Instrumentation



Data



Collaboration